

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of: )  
Hidekazu MIYAIRI et al. ) Group Art Unit: 2828  
Application No. 10/658,472 ) Examiner: Phillip Nguyen  
Filed: September 10, 2003 ) Confirmation No. 4070  
For: LASER APPARATUS, LASER ) Date: May 29, 2007  
IRRADIATION METHOD, AND  
MANUFACTURING METHOD OF  
SEMICONDUCTOR DEVICE

**AMENDMENT**

**Mail Stop RCE**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed February 26, 2007, please amend the above identified application as follows.